

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Yosuke INOMATA

Serial No: Not assigned

Filed: January 22, 2004

For: Multicrystalline Silicon Substrate and Process for
Roughening Surface Thereof

Art Unit: Not assigned

Examiner: Not assigned

**TRANSMITTAL OF INFORMATION DISCLOSURE
STATEMENT**

Mail Stop PATENT APPLICATION
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

The information disclosure statement submitted herewith is being filed concurrently with the subject application [37 C.F.R. § 1.97(b)] and contains no items of information cited in any communication from a foreign patent office in a counterpart foreign application [37 C.F.R. § 1.97(e)(1)].

If it should be determined that for any reason either an insufficient or excessive fee has been paid, please charge any insufficiency or credit any overpayment necessary to ensure consideration of the information disclosure statement for the above-identified application to Deposit Account No. 50-1314. A copy of this paper is enclosed.

Respectfully submitted,

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